



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Hou, Chien-Chou; et al.)	Examiner:	Deo, Duy Vu Nguyen
Serial No.:	10/600,377)	Art Unit:	1765
Filed:	June 20, 2003)	Our Ref:	B-5130 621033-6
For:	"METHOD OF ETCHING UNIFORM SILICON LAYER")	Date:	November 22, 2005
)	Re:	<i>Amendment and Response</i>

AMENDMENT AND RESPONSE

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the final Office Action mailed on August 23, 2005, a response to which is due no later than

November 23, 2005,

the Applicant submits this amendment pursuant to 37 C.F.R. 1.114 together with a Request for Continued Examination. Please amend the above-identified application as described below and consider the following remarks. **All amendments and remarks herein are made without prejudice.**

A Request for Continued Examination (RCE), a fee form, and requisite fee are included with this response.

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.